

Differential deposition for figurecorrections in grazing-incidence X-ray optics

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X-ray mirror fabrication at MSFC





Non-astronomical applications





Axial figure errors - Limit the resolution of the optics





Sensitivity of figure variation



Minimizing height variation \rightarrow Improves the imaging quality

Addressing profile deviations through differential deposition





Process sequence - differential deposition



NASA

Proof of concept on miniature optics



Requirements for sputtered filler material

High deposition rate
Low roughness
Good adhesion

Experiments •Filler material •Inert gas •Power •Pressure

	Pla	tinum-Xenor	1	Platinum-Argon				
power	pressure	roughness	deposition rate	power	pressure	roughness	deposition rate	
75	15	1.950	0.130	75	15	2.060	0.140	
90	15	2.043	0.230	90	15	1.933	0.190	
75	30	1.895	0.170	75	30	1.868	0.160	
90	30	1.810	0.250	90	30	2.083	0.220	
Nickel-Xenon				Nickel-Argon				
power	pressure	roughness	deposition rate	power	pressure	roughness	deposition rate	
75	15	1.915	0.290	75	15	1.995	0.180	
90	15	2.070	0.360	90	15	1.778	0.240	
75	30	3.093	0.240	75	30	2.260	0.220	
90	30	3.630	0.310	90	30	2.210	0.290	
	Tur	ngsten-Xenor	n	Tungsten-Argon				
power	pressure	roughness	deposition rate	power	pressure	roughness	deposition rate	
75	15	1.965	0.300	75	15	1.900	0.120	
75	30	1.805	0.290	75	30	2.125	0.290	
90	30	1.993	0.370	90	30	-	-	
75	50	2.075	0.290	75	50	1.998	0.310	
90	50	2.423	0.370	90	50	1.868	0.370	
Units: power-Watts, pressure-mTorr, roughness- Å rms, deposition rate – Å/sec								





Scale the process to larger size shells







- •Larger size astronomical X-ray shells
- •Use of VLTP better accuracies



Depositions





Custom vacuum chamber



Coatings on glass samples



Mask configurations

•For larger-size astronomical Xray shells

Preliminary experiments
Optimize mask design
Diameter of target rod

•Coatings on glass samples to check

•Deposition rate

•Sputtered beam profile



Theoretical performance improvement





correction

Possible practical limitations

Correction stage	Average deposition amplitude (nm)	Slit-size (mm)	Metrology uncertainty (nm)	Angular resolution (arc secs)	•Simulations performed on X-ray shell that has 8 arc sec HPD
			± 0	3.6	•Potentiality for arc-second-level
1	300	5	± 10	3.6	resolution -with existing
			± 50	7.3	
	40	2	± 0	0.6	metrology equipment
2			± 1	1	
2			± 5 <	2	•First stage of correction
			± 10	3.5	
	4	1	± 0	0.2	requires +/- 10 nm accuracy
2			± 0.5	0.2	
5			± 1	0.5	
			± 2	0.8	•Progressively finer accuracies
					required for further stages of

Refinements



• Use of customized slit to correct full length of shell at single instance



- Azimuthal variations varying rotational speed
- Use on mounted optics to correct mounting errors

Other X-ray optics



• Technique equally applicable to the planar geometry of segmented optics



- Can correct deviations low-order axial-figure errors and azimuthal axial slope the late variations in Slumped glass mirrors - one of the competing versions of ^IXO flight mirrors
- WFXT maintaining high angular resolution 5 arc sec over wide field of view avoiding shell end effects and mounting errors



Differential deposition conclusions

- Significant improvement in angular resolution of the X-ray shells is theoretically possible
- Concept proven on smaller-size medical imaging optics
- Cost-and time-efficient method of improving the imaging quality of the optics
- Profile and mounting error correction
- Can be applied to different kinds of X-ray optics full-shell as well as segmented optics